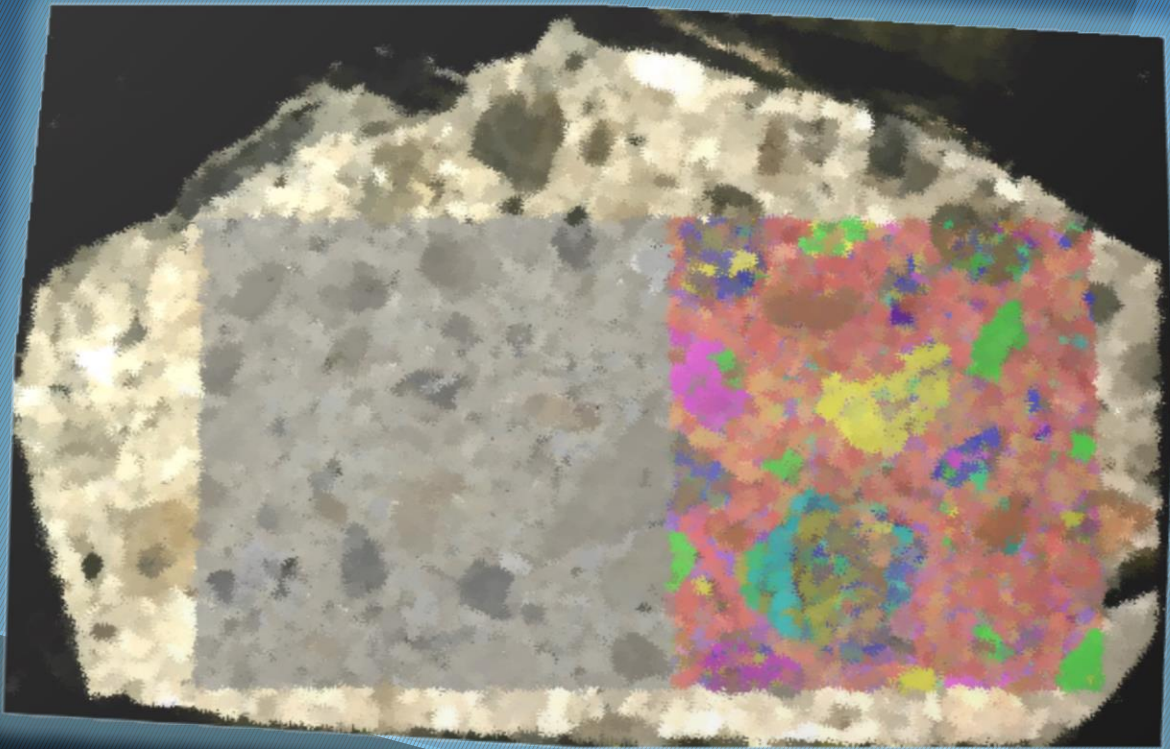




SEM SUPPORTER

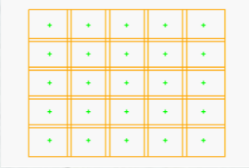


TEMography
.com

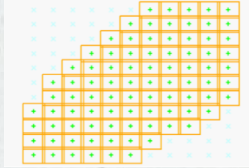
Basic Function

Automated Image Collection

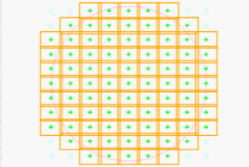
【Tile】



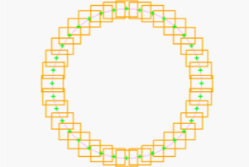
【Skip】



【Circle】



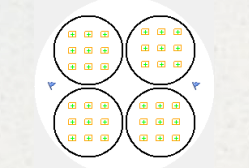
【Ring】



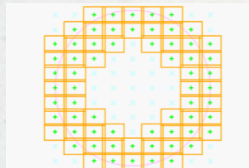
【Grid】



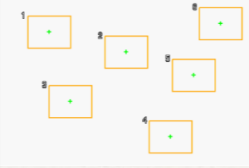
【Multi Holder】



【Doughnut】



【Free】

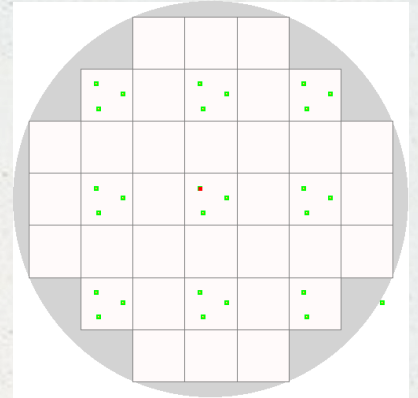


- Various layout patterns are created as templates. Chose a layout based on the application for automated image collection.
- Overlap between adjacent image frames ensures accurate montage results.
- Save the captured images as one image file. The viewer displays the composite image.

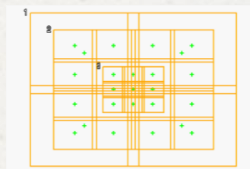
【Horizontal/Vertical】



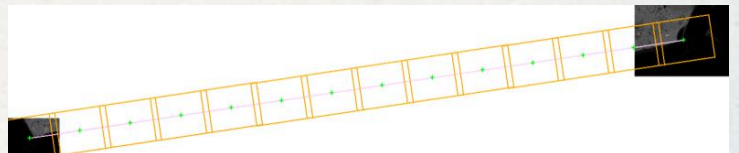
【Chip inspection】



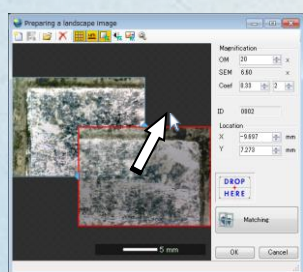
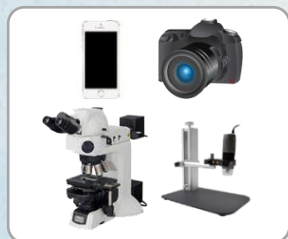
【Multiplex magnification】



【Between images】



Correlative Observation

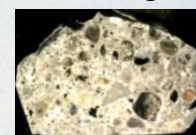


OM Image Montage

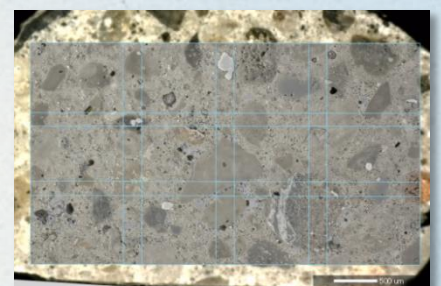
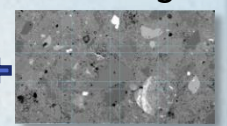
Composition : Manual operation and Automatic Montage
 《Low mag. Images - OM image Montage》

Overlay SEM Image on OM Image

OM Image



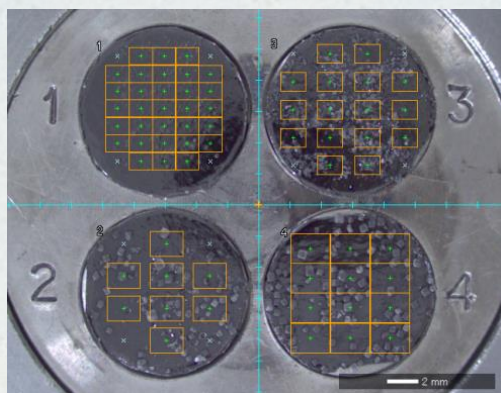
SEM Image



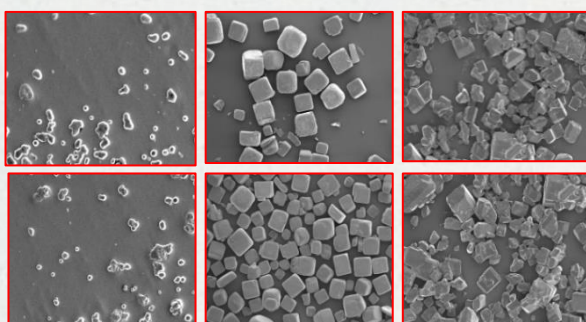
Vary the transparency.
 Can be saved as a movie.



Automatic Image Collection



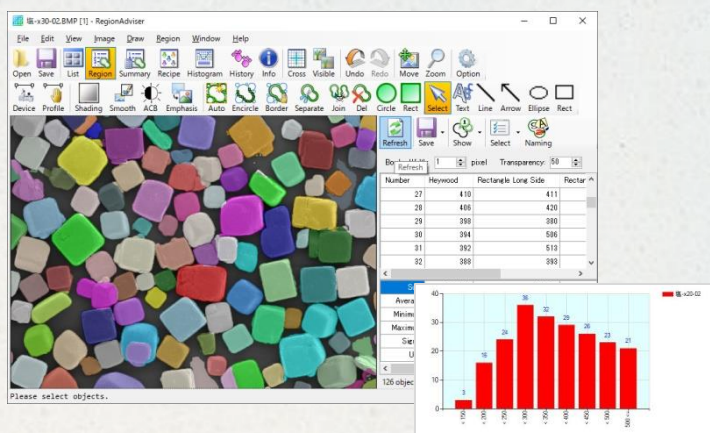
- The multiple fields of view at each sample are collected automatically.
- The particle measurement software measures feature size and parameters automatically from the SEM images.
- Multiple files can be measured using a macro.
- The graph of the frequency distribution table is saved.



Dehydrated Milk

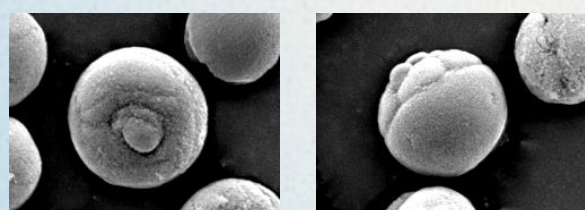
Salt

Sugar



Centering & Zoom

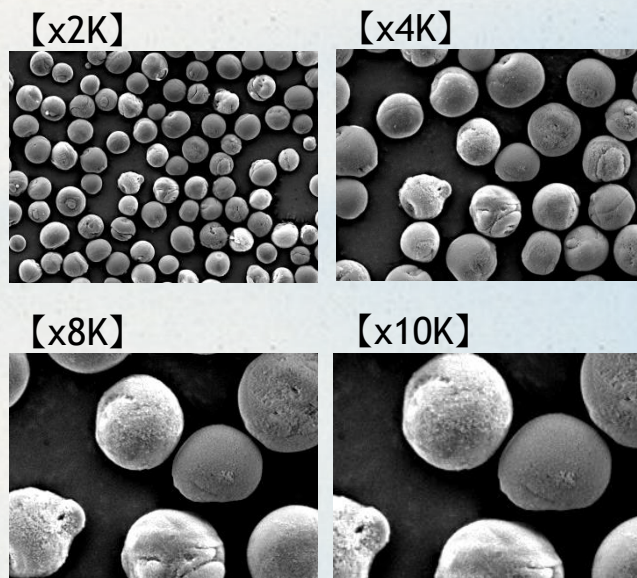
Automatically pick up any number of particles from the detected particles. Collect an image after zooming in.



※There may be a shift of the center position depending on magnification.

Multiple Magnifications

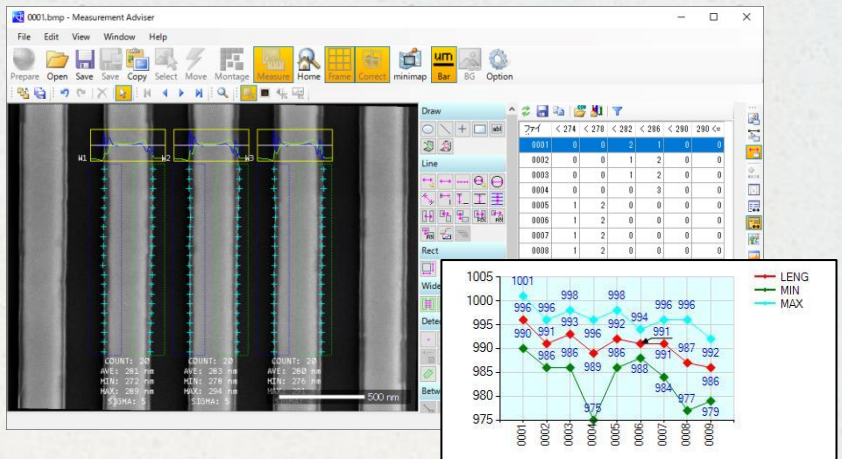
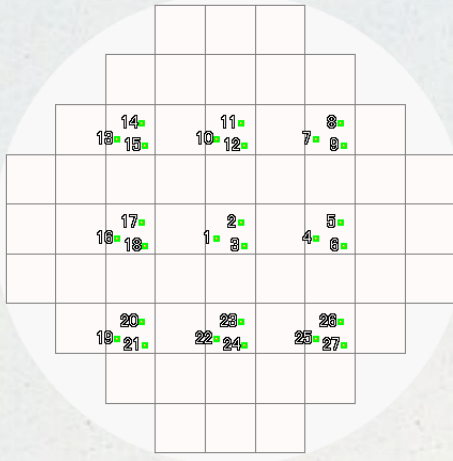
In addition to the registered magnification, images at multiple magnifications are collected at the same position.



※There may be a shift of the center position depending on magnification.

Fixed Point Observation on a Chip

- When inspecting a wafer, it is possible to easily find the same field of view within the chip.
- Using the length measurement software, the line width can be measured automatically from a contrast of a SEM image.
- Multiple files are measured using a macro.
- The frequency distribution table is saved.



Measurement Features

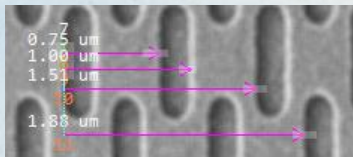
【Straight line】



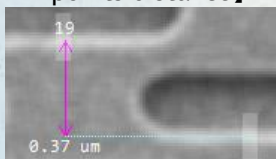
【BOX】



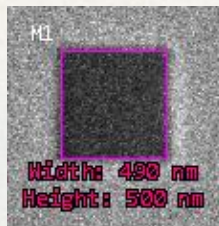
【Thickness from Fixed line】



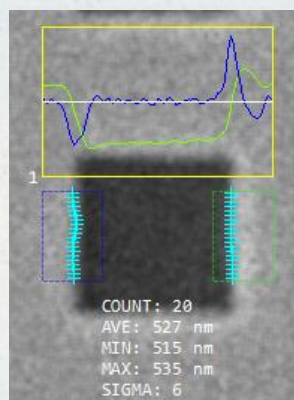
【Vertical/Horizontal-2 points distance】



【Rectangle】



【Wide】



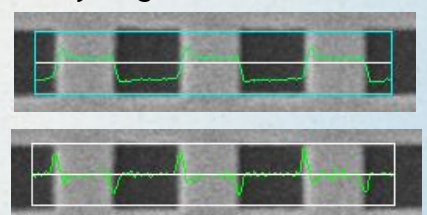
【Diameter】



【Angle】



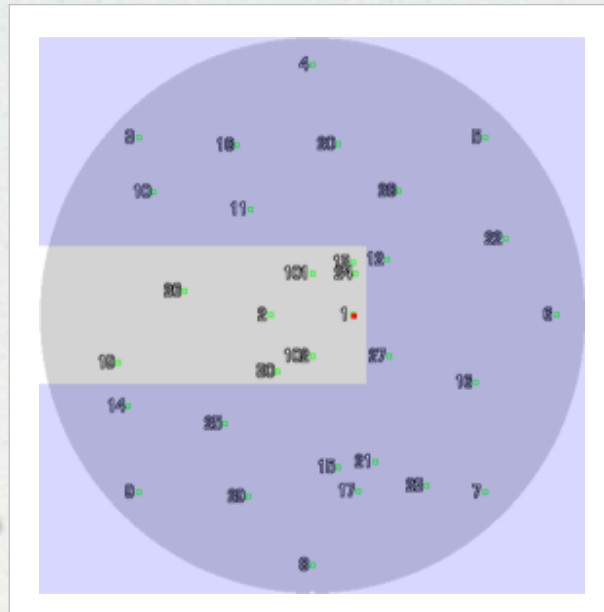
【Gray/Edge Profile】



Wafer / HDD Review

Navigate to each defect position from Wafer Inspection Result File.

Wafer / Surface Inspector



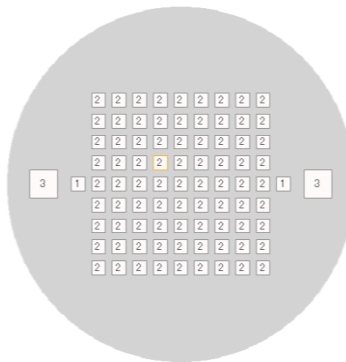
EB/CAD Navigation

Navigate by loading the chip arrangement definition file and CAD data

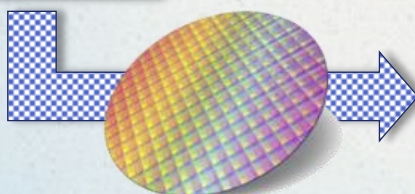
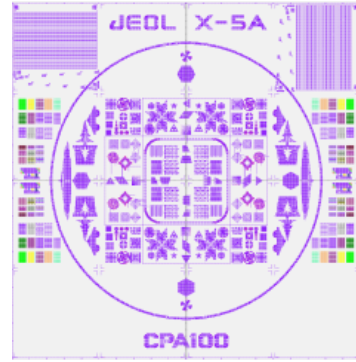
JBX



Job Deck File

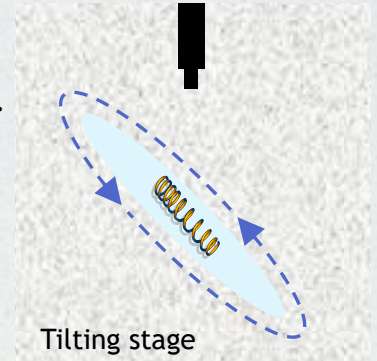


JEOL52 GDS-II/DXF



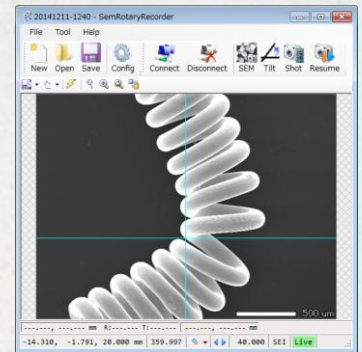
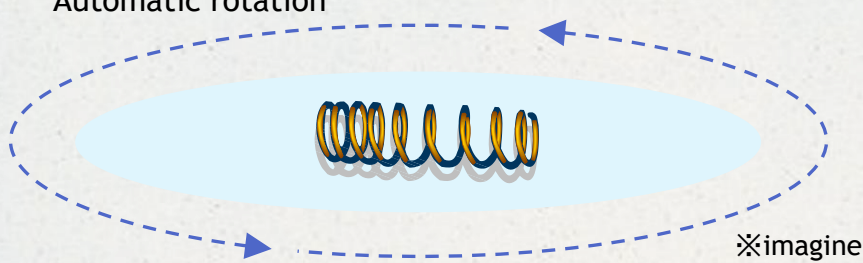
360-degree image capture

It keeps the tilt of stage and automates 360-degree image capture.

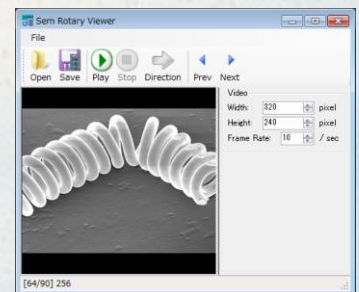
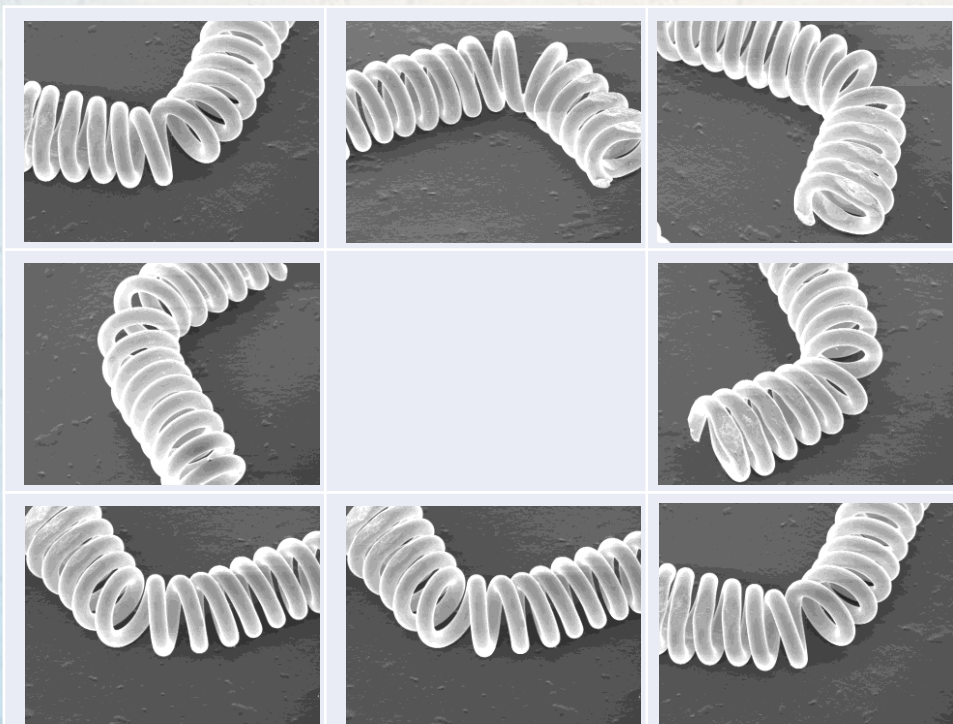


Tilting stage

Automatic rotation



Rotation Viewer



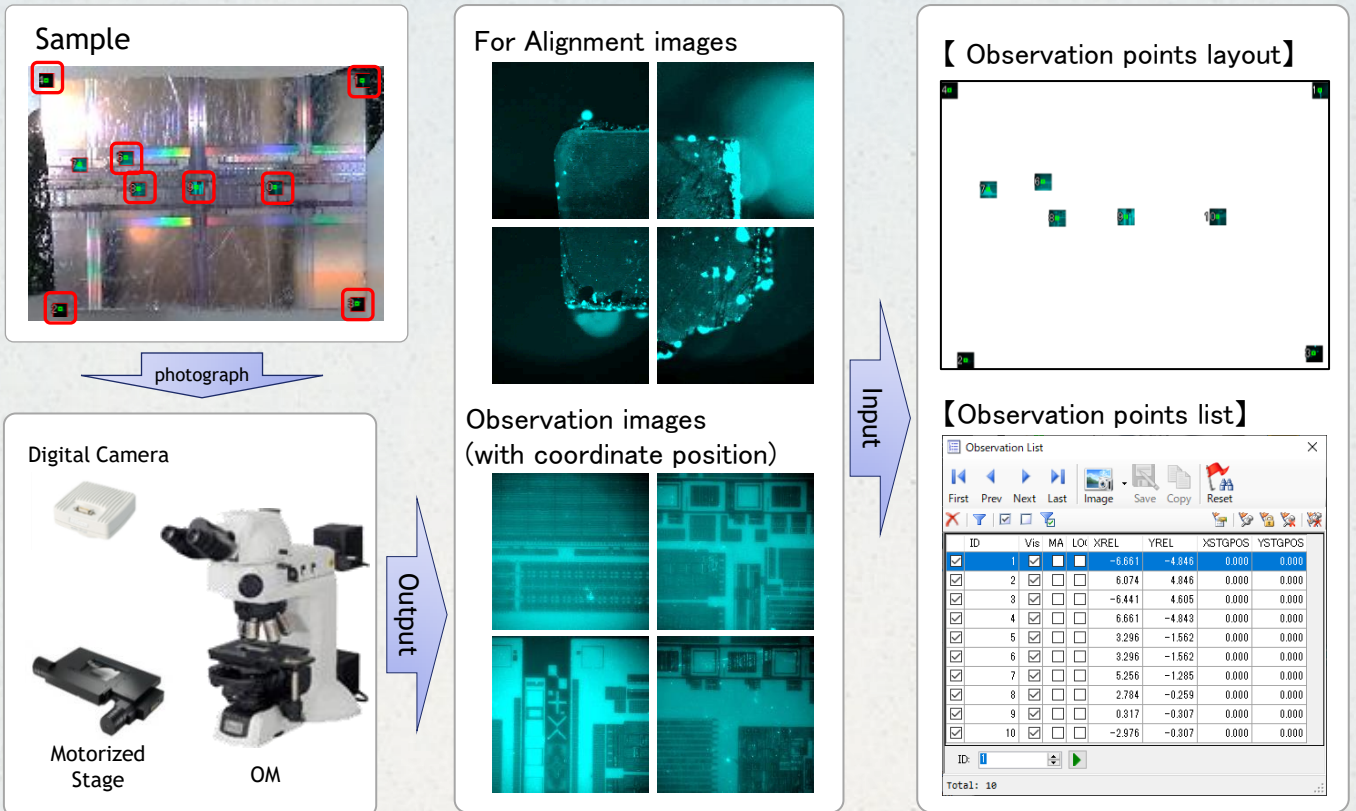
Images can save as AVI file.

Maximum number of images: 360

Extra Function

OM Linkage

Accessory

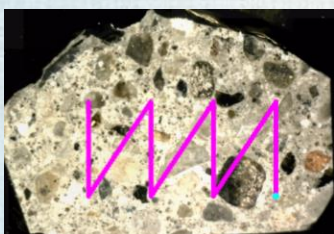
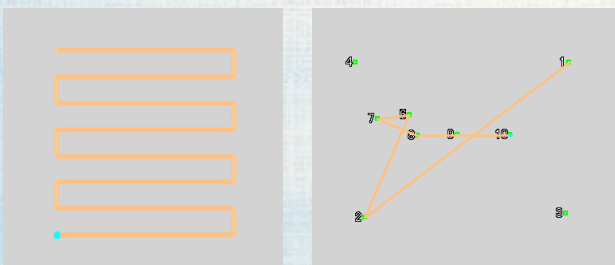


Link coordinates from OM image for navigation in the SEM with simple alignment. After alignment, the stage for SEM moves to the observation position.

By courtesy of Leica Microsystems GmbH

Stage Tracer

Accessory

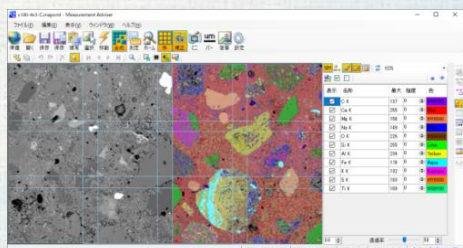


This function memorizes the stage movement. The operator can visually check the position already observed.

EDS Linkage

Accessory

The analysis image can be overlaid on the SEM image.



*only
IT100/JED-2300

Time Resolved Image Collection

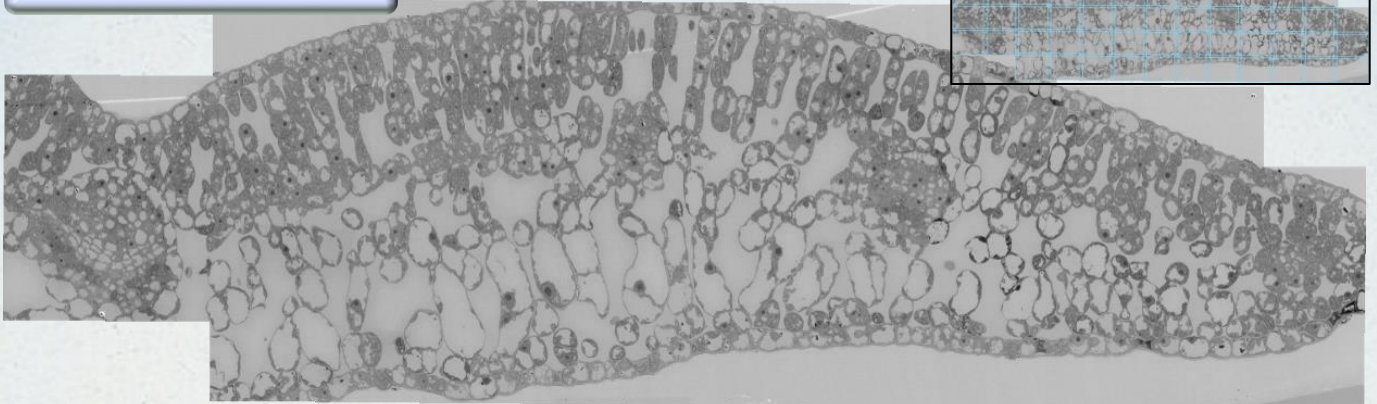
Accessory



The time resolved images can be saved as an AVI file.

Gallery

Leaf



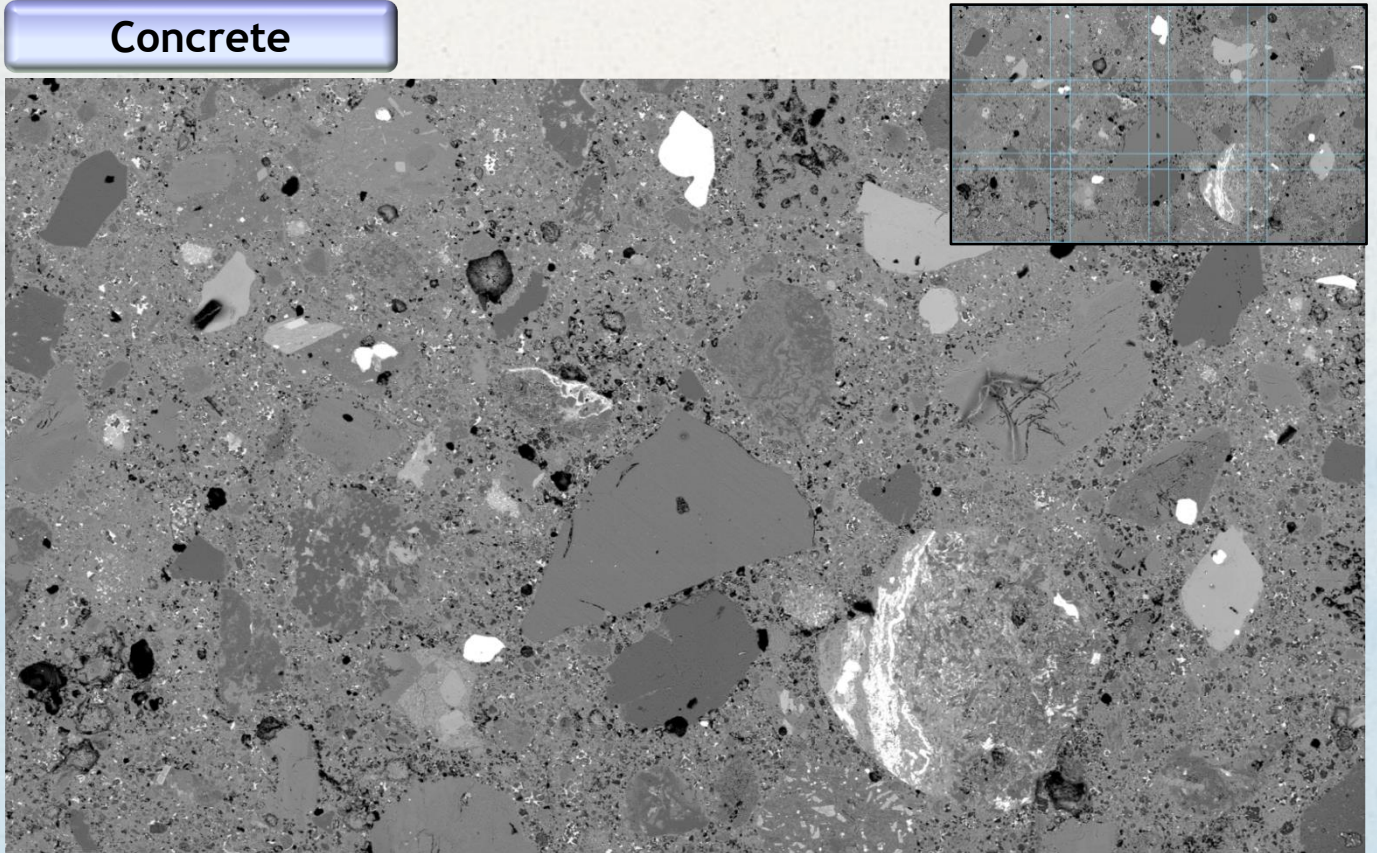
By courtesy of JEOL Ltd.

CP Cross Section



By courtesy of JEOL Ltd.

Concrete



By courtesy of JEOL Ltd.

Specifications, design and terms of offers may change without notice.

SYSTEM IN FRONTIER INC.

Address: 2-8-3 Shinsuzuharu Bldg. 4F
Akebono-cho Tachikawa-shi, Tokyo 190-0012
PH: +81-42-526-4362
Fax: +81-42-526-4370
URL: <http://temography.com/en/>



TEMography
.com

